

IBM DOCKET: FIS920000251US1

PATENT

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J. Antin

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

INVENTOR: Christopher P. Ausschnitt et al.) EXAMINER:
SERIAL NO.:) ART UNIT:
FILING DATE:) DATE: December 4, 2000
FOR: SINGLE TONE PROCESS)
WINDOW METROLOGY)
TARGET AND METHOD FOR)
LITHOGRAPHIC)
PROCESSING)

JCS31 U.S. PRO
09/734062
12/11/00

INFORMATION DISCLOSURE STATEMENT

Assistant Commissioner for Patents
Washington, D.C. 20231

Dear Sir:

In accordance with 37 CFR 1.56, 1.97 and 1.98, the following items are made of record to assist the Patent & Trademark Office in its examination of this application and is, in the opinion of the attorney designated below for applicant(s), information relevant to the closest prior art of which that person is aware. The filing of this Information Disclosure Statement shall not be construed as a representation that a search has been made or that no other art than that identified exists.

PATENT NO.

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5,712,707
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INVENTOR

Ausschnitt
Ausschnitt et al.
Ausschnitt
Koizumi et al.
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Rhyu

ISSUE DATE

May 13, 1997
January 27, 1998
March 24, 1998
May 26, 1998
May 26, 1998
July 7, 1998
September 8, 1998
June 22, 1999
July 27, 1999

<u>PATENT NO.</u>	<u>INVENTOR</u>	<u>ISSUE DATE</u>
5,949,547	Tseng et al.	September 7, 1999
5,953,128	Ausschnitt et al.	September 14, 1999
5,965,309	Ausschnitt et al.	October 12, 1999
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Intellectual Property Network, *Method for Measuring Semiconductor Lithographic Tool Focus and Exposure*, IBM Technical Disclosure Bulletin, July 1987, pages 516-518.

Alexander Starikov, *Exposure Monitor Structure* SPIE Integrated Circuit Metrology, Inspection, and Process Control IV, Vol 1261, 1990, pages 315-324

A copy of each of the foregoing items and Form PTO 1449 are enclosed herewith.

Respectfully submitted,

By:



Attorney: Peter W. Peterson

Reg. No.: 31,867

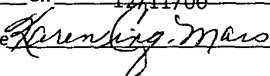
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CERTIFICATE OF MAILING UNDER 37 CFR 1.10

I hereby certify that, on the date shown below, this correspondence is being deposited with the United States Postal Service in an envelope addressed to the Assistant Commissioner for Patents, Washington, D.C. 20231, as "Express Mail Post Office to Addressee" Mailing Label No. EK140407869US on 12/11/00

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Signature



Date: 12/11/00